09/880223

IN THE CLAIMS

- 1-11. (Currently Canceled)
- 12. (Currently Amended) An array of planar T-RAM cells comprising:

a plurality of T-RAM cells, said plurality of T-RAM cells being arranged in an array and fabricated over a substrate, each of said plurality of T-RAM cells including a first-buried vertical thyristor and a second device horizontally stacked pseudo-TFT transfer gate, said first device thyristor being buried underneath said-second device transfer gate, wherein said-second device transfer gate covers the entire top surface of said-first device thyristor, and further wherein the top surface of said-second device transfer gate forms a planar top surface of each said T-RAM cell.

- 13. (Currently Canceled)
- 14. (Original) The array according to Claim 12, wherein each of the plurality of T-RAM cells has a size of less than or equal to 8F².
- 15. (Previously Amended) The array according to Claim 12, wherein said substrate is a semiconductor SOI or bulk wafer.
- 16. (Previously Amended) The array according to Claim 13, wherein a base of said thyristor is surrounded by a surrounded gate.

17. (CurrentlyAmended) The array according to Claim 12, wherein said planar top surface of each T-RAM cell provides for simplified fabrication of metal wirings wordlines, said wirings wordlines being fabricated over said planar top surface of said T-RAM cells, said wirings wordlines for interconnecting said T-RAM cells.

18-30. (Currently Canceled)

31. (New) An array of planar T-RAM cells comprising:

a plurality of T-RAM cells, said plurality of T-RAM cells being arranged in an array and fabricated over a substrate, each of said plurality of T-RAM cells including a buried vertical thyristor and a horizontally stacked pseudo-TFT transfer gate, said thyristor being buried underneath said transfer gate, said transfer gate covering a part of a top surface of said thyristor, the top surface of said transfer gate forming a planar top surface of each said T-RAM cell.